

OPENING PORTION 303 CRYSTALLINE SILICON FILM MASK 302 OPENING PORTION 303

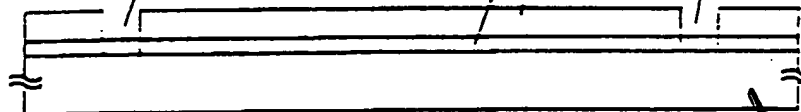


Fig. 3A

ADDING STEP OF PHOSPHORUS

301

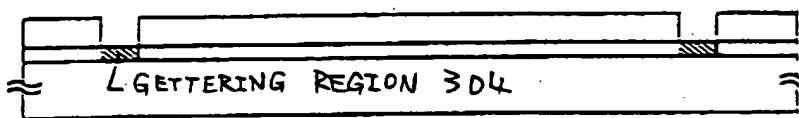


Fig. 3B

GETTERING STEP

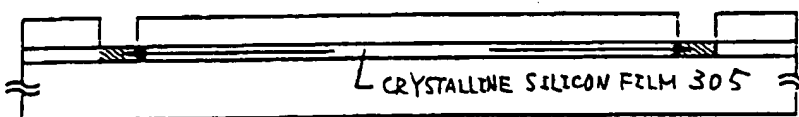


Fig. 3C

HEAT TREATMENT STEP IN REDUCING ATMOSPHERE

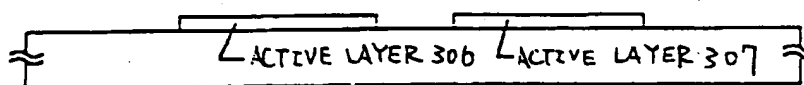


Fig. 3D

SOURCE REGION 403 N-CHANNEL TFT 401 P-CHANNEL TFT 402 SOURCE REGION 405

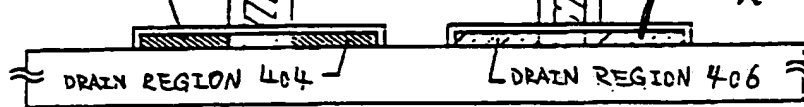


Fig. 4A

GETTERING STEP

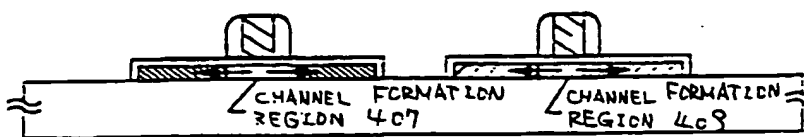


Fig. 4B